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**NOTIFICATION CONCERNING
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(PCT Administrative Instructions, Section 411)

Date of mailing (day/month/year) 14 December 2005 (14.12.2005)	To: SEMICONDUCTOR ENERGY LABORATORY CO., LTD. 398, Hase, Atsugi-shi Kanagawa 2430036 JAPON
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Applicant SEMICONDUCTOR ENERGY LABORATORY CO., LTD. et al	

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The International Bureau of WIPO 34, chemin des Colombettes 1211 Geneva 20, Switzerland Facsimile No. +41 22 338 82 70	Authorized officer Honda Masashi Facsimile No. +41 22 338 70 10 Telephone No. +41 22 338 82 54
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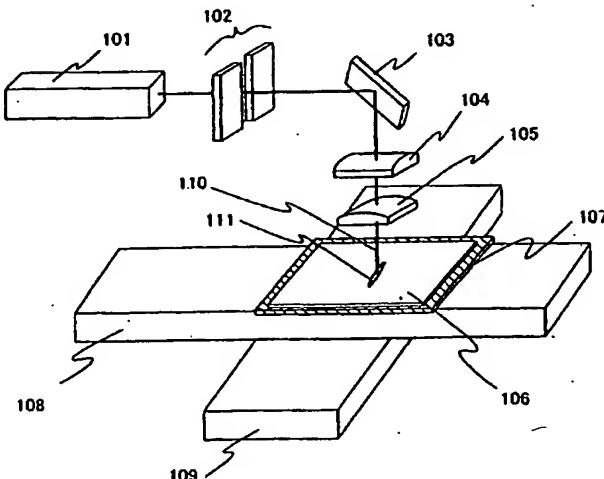
(71) Applicant (for all designated States except US): SEMICONDUCTOR ENERGY LABORATORY CO., LTD.
[JP/JP]; 398, Hase, Atsugi-shi, Kanagawa 2430036 (JP).

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(54) Title: LASER IRRADIATION METHOD, LASER IRRADIATION APPARATUS AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE



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(57) Abstract: In conducting laser annealing using a CW laser or a quasi-CW laser, productivity is not high as compared with an excimer laser and thus, it is necessary to further enhance productivity. According to the present invention, a fundamental wave is used without putting laser light into a non linear optical element, and laser annealing is conducted by irradiating a semiconductor thin film with pulsed laser light having a high repetition rate. A laser oscillator having a high output power can be used for laser annealing, since a non linear optical element is not used and thus light is not converted to a harmonic. Therefore, the width of a region having large grain crystals that is formed by scanning once can be increased, and thus the productivity can be enhanced dramatically.